

Notice of References Cited	Application/Control No. 10/735,742	Applicant(s)/Patent Under Reexamination LIM ET AL.	
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*	E	US-6,153,480	11-2000	Arghavani et al.	438/296
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*	G	US-6,709,951	03-2004	Beyer et al.	438/424
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
*	U	Stanley Wolf and Tauber N. Richard, Silicon Processing For The VLSI Era, 2000, Lattice Press, Second Edition, pgs. 277-283
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.